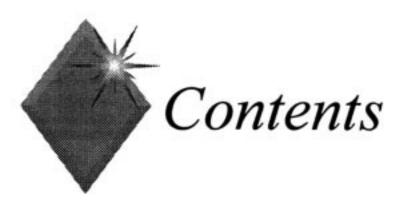
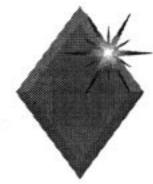


1997 Southwest Test Workshop June 2, 1997

Presented by: Earl Eddy



- ◆ Purpose of Probe Mark Inspection
- ◆ Function of Probe Mark Inspection
- Specification
- ◆ Result Evaluation
- ◆ Pad Registration, Including Unique Shapes
- ◆ Examples
- Conclusion



Why Probe Mark Inspect?

- ◆ To Verify Actual Contact Position by Probe Mark Prior to Probing
- ◆ To Verify That There Is No Problem With the Contact While Probing



Probe Mark Inspect Function

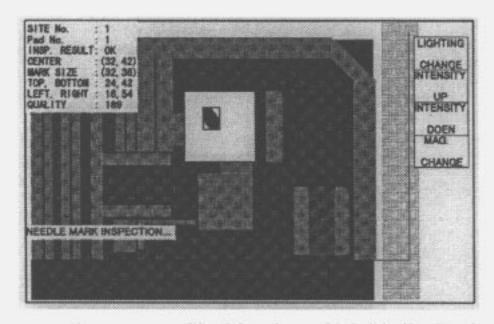
- ◆ To Analyze the Probe Mark Made on the Pad by High Magnification Alignment Camera.
 - ◆ Off-Position Judgment -- To Judge If Periphery Of Probe Mark Is Inside Selected Position
 - ◆ Size Judgment -- To Compare the Size of the Probe Mark to a Minimum and Maximum Value
- ◆ Result Output -- To Show Position and Measurement Data on Screen and Print Out



Left, Right

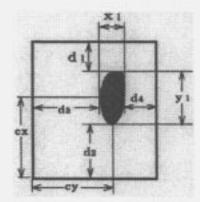
Data Output (Screen Display)

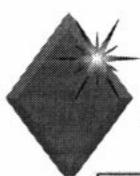
Mark Distance to Edge (d3,d4)



Site No. Site Number of Multi-die Card Pad No. Pad Number Insp Result : OK Result (OK or Rejected) Center of Mark (cx,cy) Center : (32,42) Mark Size : (32,36) Size of Mark (x1,y1) Mark Distance to Edge (d1,d2) Top, Bottom : 24,42

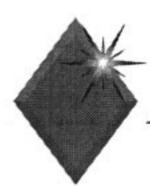
: 16,54



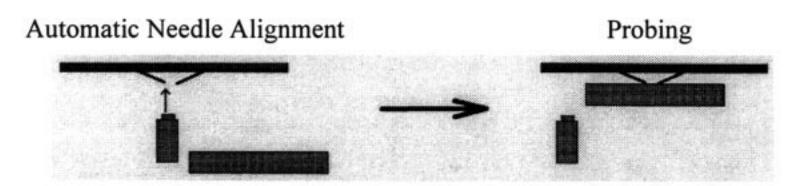


Pata Output (Printout)

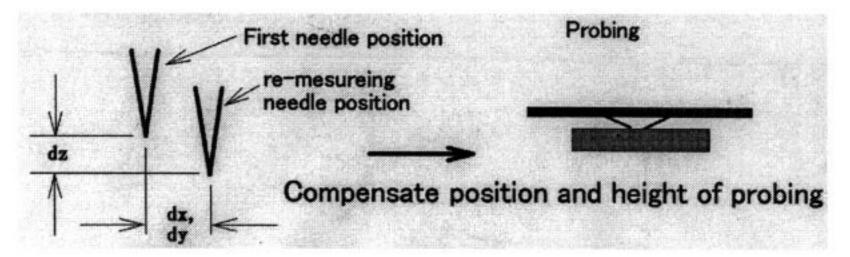
```
esses Wafer Information esses
DEVICE
                        TEST
Wefer ID
                        T-12345678
Cassette No.
Sigt No.
Rafer size
Index size X
Index size Y
                       : 6504.00 um
Flat/notch direction
                     : 180 deg
Temperature Control
Chuck Temperature
Multi Probing Setting : 2
Registered Peda
     Needle Mark Inspection Data
                 Site coordinator
                                              Y = 11
                                     Bottom
                                               Left
                              Top
```

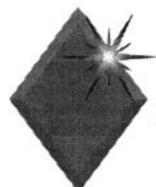


Probe Position Control



Remeasure Needle Position at Some Interval & Compensate





Inspection Timing

- ◆ Inspection Is Performed After Die Test
- ◆ Timing Parameters
 - Wafer Interval
 - ◆ Die Interval
 - Wafer Map Selection -- Can Target Specific
 Die to Inspect on the Wafer Map



Pad Inspection Selection

All Pads

- ◆ Inspect All Registered Pads
- ◆ Manual Select
 - ◆ Inspect User Selected Pads From the Set of Registered Pads
- ◆ Auto Select
 - ◆ Inspect All Registered Pads First. Prober Then Selects 4 or More Probe Marks Nearest to Pad Edge. Subsequent Inspections of Those Pads Only



Max # Registered Pads 512 Pads

Pad Size Max 400 X 350 μm

Min 30 µm (Narrow Side)

Detectable Probe Mark Max Within Pad Size

Min $100 \, \mu m^2$

Inspection Accuracy 2.0 µm

Processing Speed ~ 500 msec/Pad

(100x100 µm Pad)

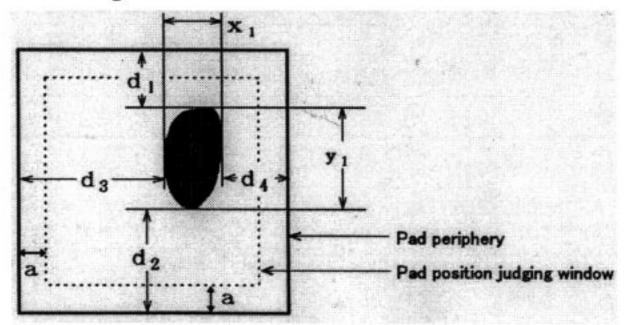


Judgment Results

◆ Off-Position Judgment: OK if dn ≥a (n=1~4)

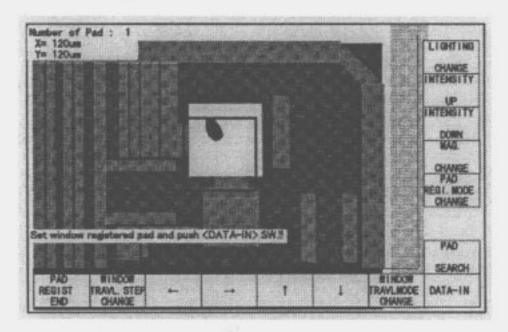
♦ Size Judgment: OK if Min ≤x1&y1≤ Max

♦ Area Judgment: OK if Min ≤area≤ Max





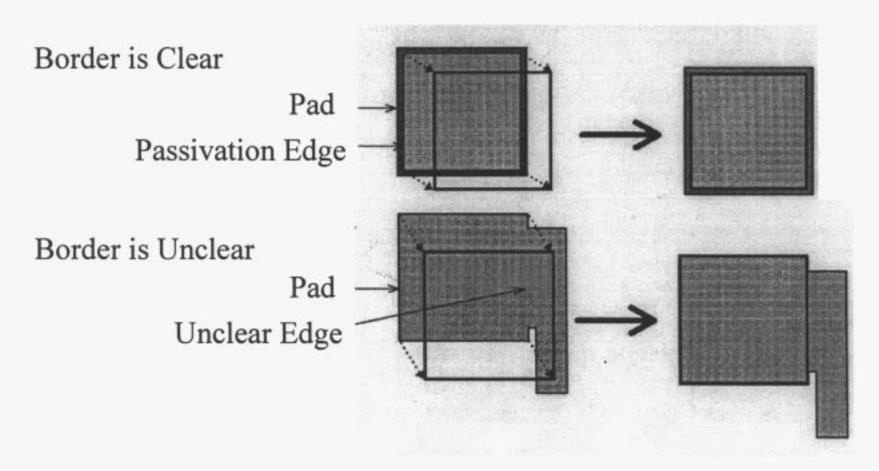
Pad Registration

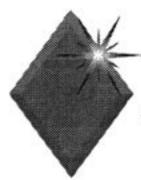


- Before Inspection, Pad Position And Size Must Be Registered
- Registration Process
 - Use The Arrows To Size the Registration Window Then "Data-In"
 - Position Pad Under Window and Press Pad Search



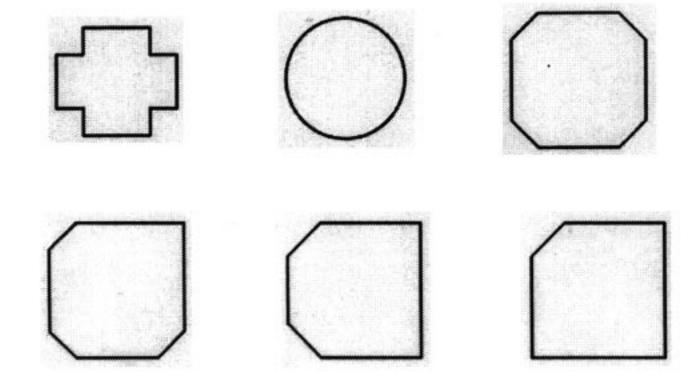
Determine Pad Size & Place Pad Under Registration Window

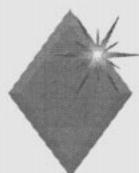




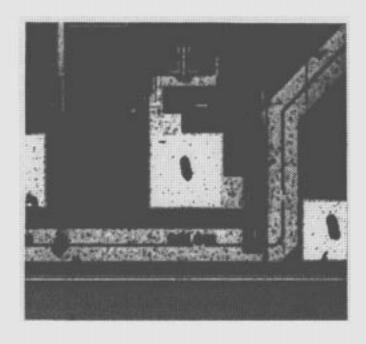
Inspection of Non-Square Pads

Examples of Acceptable Pad Shapes

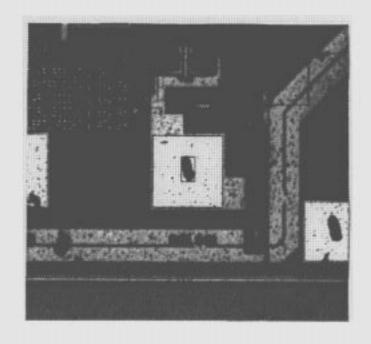




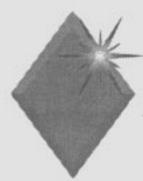
Inspection Example



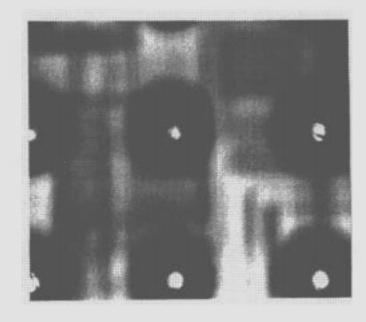
Before Inspection



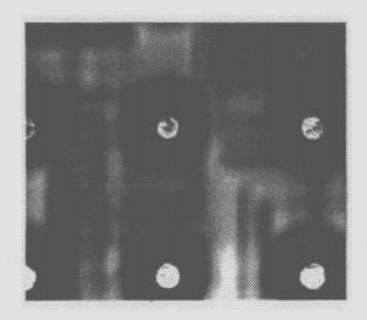
After Inspection Results & Data Shown



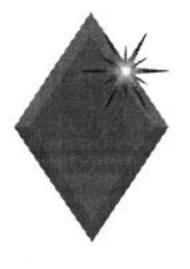
Inspection of Solder Bumps







After Probe



Conclusion

Any Questions?